

09/01/01  
JC9690 U.S. PTO

09-04-01

A

PATENT

Express Mail # EL856120045  
Docket No. 1641008

09/01/01  
JC973 U.S. PTO

**NEW APPLICATION TRANSMITTAL - UTILITY**

Transmitted herewith for filing is the patent application of Wu-Niang FENG for "SEMICONDUCTOR WASTE-GAS TREATING APPARATUS BEING FILTH-SEDIMENTATION-, AND ETCHING-PROOF".

**1. Type Of Application**

This application is an original utility application.

**2. Benefit Of Prior Application**

Applicant claims no benefit of prior application.

**3. Fee Calculation**

CLAIMS AS FILED

Basic Fee = \$355.00

Total:        9 - 20 = 0 x \$ 9.00 =        0.00

Ind.:        2 - 3 = 0 x \$40.00 =        0.00

Multiple dependent:    0 x \$135.00 =        0.00

Basic Filing Fee Calculation = \$355.00

**4. Small Entity Statement**

Applicant is entitled to Small Entity Status.

**5. Fee Payment Being Made At This Time**

Required Fees:

x Basic Filing Fee                  \$355.00

**Total Fees**                  **\$355.00**

Please charge the above and any deficiencies in fees to Deposit Acct # 16-2497.

6. Papers Enclosed Which Are Required For Filing Date Under 37 CFR 1.53(b)

7 Pages of specification

2 Pages of claims

1 Page of abstract

8 Sheets of formal drawings

7. Declaration or Oath

A Combined Declaration and Power of Attorney executed by each inventor is enclosed herewith.

8. Inventorship Statement

The inventorship is the same for all the claims in this application.

9. Certificate of Mailing (37 CFR 1.10): I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as Express Mail in an envelope addressed to: Box New Applications, The Assistant Commissioner for Patents, Washington, D.C. 20231.

Respectfully submitted,



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